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(JTETC/JSA)

Testing methods for electrostatic propensity of woven and knitted fabrics

(Amendment 1)

JIS L 1094: 2014 was revised under date of February 20, 2020. This Amendment includes the revised items and is to be used in conjunction with **JIS L 1094:** 2014.

ICS 59.080.30

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Foreword

This Japanese Industrial Standard has been revised by the Minister of Economy, Trade and Industry through deliberations at the Japanese Industrial Standards Committee in accordance with the Industrial Standardization Act.

This Amendment partially replaces the previous edition (**JIS L 1094**:2014), which has been technically revised.

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